

ABSTRACT OF THE DISCLOSURE

The semiconductor wafer containment device or wafer box includes a base with a planar floor and a cylindrical wall arising therefrom. A double concentric wall structure includes slots which receive body chip wafer pins which extend into the space formed between the inner cylindrical wall and the wafer so as to cushion the semiconductor wafers and prevent movement of the semiconductor wafers during transportation. Alternately, a single cylindrical wall includes slots which receive extruded finned pins which include fins which extend inward into the space formed within the cylindrical wall so as to cushion the semiconductor wafers and prevent movement of the semiconductor wafers during transportation. The semiconductor wafer containment device or wafer box further includes a lid which is engaged by the base thereby capturing the extruded finned pins during transportation.